

| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|-------|------|---|--|------------------|---------|------------------|
| L1 | 164 | (microstructures or micromachine) same etch\$3 same vapor | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 07:42 |
| L2 | 267 | (microstructures or micromachine or MEMS) same etch\$3 same vapor | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 09:28 |
| L4 | 28 | (microstructures or micromachine or MEMS) same (vapor with etch) | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 07:52 |
| L5 | 243 | (microstructures or micromachine or MEMS) and (vapor with etch) | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 07:52 |
| L6 | 97 | (microstructures or micromachine or MEMS) and (vapor with etch) and (recipe or parameters) | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 09:05 |
| L7 | 1 | "5302238".PN. | USPAT; USOCR | OR | OFF | 2005/05/04 09:04 |
| L8 | 273 | (microstructures or micromachine or MEMS) same (aluminum or copper) same TiN | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 09:08 |
| L11 | 778 | (microstructures or micromachine or MEMS) and (etch\$3 or remov\$3) and (vapor with etch\$3) | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 09:30 |
| L12 | 263 | (microstructures or micromachine or MEMS) and (etch\$3 or remov\$3) and (vapor with etch\$3) and (HF or "xeF.sub.2" or "xenon difluoride" or "bromine trichloride") | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 09:32 |
| L13 | 400 | (microstructures or micromachine or MEMS) and (etch\$3 or remov\$3) and (vapor with etch\$3) and (recipe or window or parameters) | USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/05/04 09:32 |